

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	1433682	(microelectromechanical or micro-electromechanical or micro-electro-mechanical or (micro adj2 electromechanical) or (micro adj2 electro aj2 mechanical)) or MEMS	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:21
L2	35683	((first or primary or top) adj2 layer\$1) with silicon	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:24
L3	7490505	(hydrogen\$4 adj2 treatment) or (hydrogen\$4 ad2j surface\$1)	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:24
L4	27891	((second\$3 or bottom) adj2 layer\$1) with silicon	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:24
L5	21185	2 and 4	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:23
L6	7233	1 and 5	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:23
L13	6322	(hydrogen\$4 adj2 plasma)	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:25
L15	13	(((second\$3 or bottom) adj2 layer\$1) with silicon) same ((hydrogen\$4 adj2 treatment) or (hydrogen\$4 adj2 surface\$1))	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:28
L16	24	(((first or primary or top) adj2 layer\$1) with silicon) same ((hydrogen\$4 adj2 treatment) or (hydrogen\$4 adj2 surface\$1))	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:29
L17	11	15 and 16	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 11:16
L18	2	1 and 17	US-PGPUB; USPAT; EPO; JPO; DERWENT	OR	OFF	2005/04/29 10:30